

# EUROPEAN PATENT OFFICE

## Patent Abstracts of Japan

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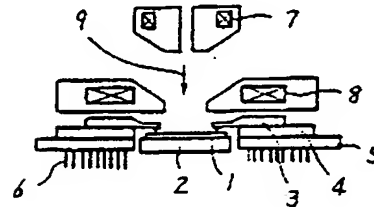
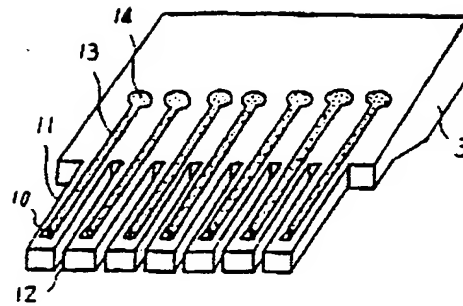
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TITLE : MICROPROBER



ABSTRACT : PURPOSE: To array probes with high density, to obtain a pointed probe to prevent an electric field from being disordered owing to wiring by forming a beam structure and a probe structure which projects vertically in the same body with a single crystal body.

CONSTITUTION: A wafer 1 which has elements to be inspected on the surface is fixed on a movable table 2 and individual signal lines and feed lines on the wafer are probed by a probe substrate 3. The tracers 10 of the probe- substrate 3 and the beam structure 11 which receive a force for pressing the probes are formed of silicon single crystal in integrated structure. Slits 12 are formed in the beam structure 11 so as to enable the tips of all the probes to enter probing operation even if the surface of a body to be measured have unevenness. The signal and feed lines 13 are guided on the surface of the beam structure and terminated by pads 14, and signals are led out to an external connection substrate 5 from the pads 14 through a through hole substrate 4.

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